Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A deposition source installed in a chamber, heated by applied electric power to transfer heat to a vapor deposition material received therein and applying a vaporized deposition material generated therein to a substrate to form deposition organic electroluminescent layers onto the substrate, comprising;

a vessel ~~consisted of~~ comprising a top plate on which a vapor efflux aperture is formed, a side wall, and a bottom wall;

a heating means for supplying heat to the deposition material received in said vessel, said heating means being capable of moving vertically;

a sensing means for sensing varied distances between said heating means and the surface of said deposition material; and

a means for moving said heating means, said moving means being operated in response to ~~the~~ a signal of ~~a~~ the sensing means on the varied distances between said heating means and the surface of said deposition material, whereby said heating means is moved downward by said moving means to maintain the distance between said heating means and the surface of the deposition material at an initially-set value when the thickness of the deposition material is decreased, wherein said side wall has a number of vertical grooves formed on the

inner surface thereof, and said top plate has a number of protrusions formed on the outer circumference surface thereof, each of said protrusions has such a size that each protrusion can be received in each of said grooves so that each of said protrusions of said top plate is moved along each of said grooves of said side wall when said top plate is moved vertically.

2. (Original) The deposition source according to claim 1, wherein said sensing means and said heating means are mounted to said top plate, said moving means comprises a number of cylinders supported by said chamber and for moving said top plate vertically with having rods fixed to said top plate; and a control means receiving a signal from said sensing means and controlling said cylinders in response to the transmitted signal, whereby said cylinders make said top plate move downward along said side wall when the distance between said top plate and said deposition material is larger than the initially-set value.

3. (Original) The deposition source according to claim 2, wherein each of said cylinders is installed at the outer side which does not correspond to said vapor efflux aperture formed on said top plate so that each of said cylinders does not affect the flow of vapor of said deposition material escaped through said vapor efflux aperture.

4. (Canceled)

5. (Currently Amended) A deposition source installed in a chamber, to form deposition organic electroluminescent layers onto the substrate, by applying a vaporized deposition material generated therein to a substrate, by transferring heat to a vapor deposition material received therein, heated by applied electric power, comprising;

a vessel ~~consisted of~~ comprising a top plate on which a vapor efflux aperture is formed, a side wall, and a bottom plate, said bottom plate being capable of moving vertically;

a heating means for supplying heat to said deposition material received in said vessel;

a sensing means for sensing varied distances between said heating means and the surface of said deposition material; and

a means for moving said bottom plate, said moving means being operated in response to ~~the~~ a signal of ~~a~~ the sensing means on the varied distances between said heating means and the surface of said deposition material, whereby said bottom plate is moved upward by said moving means to maintain the distance between said heating means and the surface of the deposition material and the distance between said substrate to be coated and the surface of the deposition material at an initially-set value when the thickness of the deposition material is decreased, wherein said side wall has a number of vertical grooves formed on the inner surface thereof, and said bottom plate has a number of protrusions formed on the outer circumference surface thereof, each of said protrusions has such a size that each protrusion can be received in

each of said grooves so that each of said protrusions of said bottom plate is moved along each of said grooves of said side wall when said bottom plate is moved vertically.

6. (Original) The deposition source according to claim 5, wherein said moving means comprises

a cylinder supported by said chamber and for moving vertically said bottom plate with having a rod fixed to said bottom plate; and

a control means receiving a signal transmitted from said sensing means mounted to said top plate and controlling said cylinder in response to the transmitted signal, whereby said cylinder makes said bottom plate move upward along said side wall when the distance between said heating means and the surface of said deposition material is larger than the initially-set value.

7. (Canceled)

8. (Original) The deposition source according to claim 5, wherein said sensing means is an optical sensor.

9-23. (Canceled)

24. (New) A deposition source installed in a chamber, heated by applied electric power to transfer heat to a vapor deposition material received therein and applying a vaporized deposition material generated therein to a substrate to form deposition organic electroluminescent layers onto the substrate, comprising;

a vessel comprising a top plate on which a vapor efflux aperture is formed, a side wall, and a bottom wall;

a heating device configured to supply heat to the deposition material received in said vessel, said heating device being capable of moving vertically;

a sensing device configured to sense varied distances between said heating device and the surface of said deposition material; and

a moving device configured to move said heating device, said moving device being operated in response to a signal of the sensing device on the varied distances between said heating device and the surface of said deposition material, whereby said heating device is moved downward by said moving device to maintain the distance between said heating device and the surface of the deposition material at an initially-set value when the thickness of the deposition material is decreased, wherein said side wall has a number of vertical grooves formed on the inner surface thereof, and said top plate has a number of protrusions formed on the outer circumference surface thereof, each of said protrusions has such a size that each protrusion can be received in each of said grooves so that each of said protrusions of said top plate is moved along each of said grooves of said side wall when said top plate is moved vertically.

25. (New) The deposition source according to claim 24, wherein said sensing device and said heating device are mounted to said top plate, said moving device comprises a number of cylinders supported by said chamber and for moving said top plate vertically with having rods fixed to said top plate; and a control device configured to receive a signal from said sensing device and control said cylinders in response to the transmitted signal, whereby said cylinders make said top plate move downward along said side wall when the distance between said top plate and said deposition material is larger than the initially-set value.

26. (New) The deposition source according to claim 25, wherein each of said cylinders is installed at the outer side which does not correspond to said vapor efflux aperture formed on said top plate so that each of said cylinders does not affect the flow of vapor of said deposition material escaped through said vapor efflux aperture.

27. (New) A deposition source installed in a chamber, to form deposition organic electroluminescent layers onto the substrate, by applying a vaporized deposition material generated therein to a substrate, by transferring heat to a vapor deposition material received therein, heated by applied electric power, comprising;

a vessel comprising a top plate on which a vapor efflux aperture is formed, a side wall, and a bottom plate, said bottom plate being capable of moving vertically;

a heating device configured to supply heat to said deposition material received in said vessel;

a sensing device configured to sense varied distances between said heating device and the surface of said deposition material; and

a moving device configured to move said bottom plate, said moving device being operated in response to a signal of the sensing device on the varied distances between said heating device and the surface of said deposition material, whereby said bottom plate is moved upward by said moving device to maintain the distance between said heating device and the surface of the deposition material and the distance between said substrate to be coated and the surface of the deposition material at an initially-set value when the thickness of the deposition material is decreased, wherein said side wall has a number of vertical grooves formed on the inner surface thereof, and said bottom plate has a number of protrusions formed on the outer circumference surface thereof, each of said protrusions has such a size that each protrusion can be received in each of said grooves so that each of said protrusions of said bottom plate is moved along each of said grooves of said side wall when said bottom plate is moved vertically.

28. (New) The deposition source according to claim 27, wherein said moving device comprises:

a cylinder supported by said chamber and for moving vertically said bottom plate with having a rod fixed to said bottom plate; and

a control device configured to receive a signal transmitted from said sensing device mounted to said top plate and control said cylinder in response to the transmitted signal, whereby said cylinder makes said bottom plate move upward along said side wall when the distance between said heating device and the surface of said deposition material is larger than the initially-set value.

29. (New) The deposition source according to claim 27, wherein said sensing device is an optical sensor.